

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Prior Application: M. ISHIBASHI et al
 Serial No. 09/090,942
 Filed: June 5, 1998

J1050 U.S.PTO
 10/050814
 01/18/02

Group Art Unit: 2851
 Examiner: P. Kim
 For: ELECTRON EXPOSURE APPARATUS

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
 Washington, D.C. 20231

January 18, 2002

#13
 3/26/02
 M. Stanger

Sir:

In accordance with the duty of disclosure, the applicants inform the Examiner of the documents cited during prosecution of the parent application, USSN 09/090,942.

The applicants request the Examiner to initial and return a copy of the attached PTO-1449 form as an indication that the references have been considered.

Respectfully submitted,


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FORM PTO-1449 (REV. 7-80)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. NIT-92-02	SERIAL NO.
LIST OF DOCUMENTS CITED BY APPLICANT <i>(Use several sheets if necessary)</i>				APPLICANT M. ISHIBASHI et al	
				FILING DATE January 18, 2002	GROUP

U.S. PATENT DOCUMENTS

* EXAMINER INITIAL	DOCUMENT	DATE	NAME	CLASS	SUBCLASS	FILING DATE (If Appropriate)
AA	5,666,190	09/09/97	Quate et al			
AB	5,049,461	09/17/91	Arnett et al			
AC	5,546,375	8/13/96	Shimada et al			
AD	5,793,040	08/11/98	Oguchi et al			
AE	5,546,374	08/13/96	Kuroda et al			J1050 10/050814 01/18/02
AF	5,536,988	07/16/96	Zhange et al			
AG	5,431,055	07/11/95	Takata et al			
AH	5,150,392	09/22/92	Hohn et al			
AI						
AJ						
AK						

FOREIGN PATENT DOCUMENTS

	DOCUMENT	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES	NO
AL						<input type="checkbox"/>	<input type="checkbox"/>
AM						<input type="checkbox"/>	<input type="checkbox"/>
AN						<input type="checkbox"/>	<input type="checkbox"/>
AO						<input type="checkbox"/>	<input type="checkbox"/>
AP						<input type="checkbox"/>	<input type="checkbox"/>

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

AR		APPLIED PHYSICS LETTERS, Vol. 66, No. 6, Feb 6, 1995, "Fabrication of 0.1um metal oxide semiconductor field-effect transistors with the atomic force microscope," S.C. Minne et al, pp. 703-705.
AS		1997 SYMPOSIUM ON VLSI TECHNOLOGY, "Fabrication on 100nm pMOSFETs with Hybrid AFN/STM Lithography", Soh et al.
AT		

EXAMINER	DATE CONSIDERED
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* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.